



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
PETITION FOR EXTENSION OF TIME FROM THE OFFICE ACTION

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on October 23, 2008.

Shannon L. Stewart

Applicant : Kim, Nam Hun
Application No. : 10/593,857
Filed : September 22, 2006
Title : PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND
METHOD FOR ETCHING THE WAFER USING THE SAME

Confirmation No. 5813

Grp./Div. : 1792
Examiner : Duy Vu Nguyen Deo
Docket No. : 58409/N305

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Post Office Box 7068
Pasadena, CA 91109-7068
October 23, 2008

Commissioner:

Applicant petitions the Commissioner to extend the time for response to the Office action dated June 23, 2008 for one month(s) from September 23, 2008 to October 23, 2008.

The fee for extension of time required by 37 CFR § 1.17 is calculated below.

FEE CALCULATION			
LENGTH OF EXTENSION	SMALL ENTITY	LARGE ENTITY	FEE
WITHIN FIRST MONTH	\$ 65.00	\$ 130.00	\$65.00

Submitted herewith is a check for \$65.00 to cover the cost of the extension.

The Commissioner is hereby authorized to charge any fees under 37 CFR 1.16 and 1.17 which may be required by this paper to Deposit Account No. 03-1728. Please show our docket number with any charge or credit to our Deposit Account. **A copy of this letter is enclosed.**

Respectfully submitted,
CHRISTIE, PARKER & HALE, LLP

By

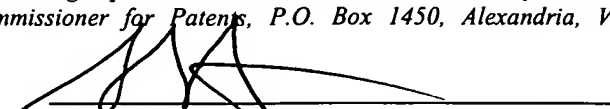
Peter C. Hsueh
Reg. No. 45,574
626/795-9900



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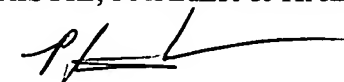
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